

Notice of References Cited

Application/Control No.

09/922,974

Applicant(s)/Patent Under
Reexamination
BLOOMSTEIN ET AL.

Examiner

Kripa Sagar

Art Unit

1756

Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,182,056	01-1993	Spence et al.	250/492.1
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	C.C.Chen and P.A.Sullivan; "Predicting Total Build-time and the Resultant Cure Depth of 3D Stereolithography Process"; Rapid Prototyping JI.; v2,(4), 1996, p.27-40
	V	Michael Gale et al.; "Fabrication of Continuous Relief Micro-Optical Elements by Direct Laser Writing in Photoresists"; Opt.Engg. v33 (11), 1994; pp. 3556-3566
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.